

LETTERS

Degassing a vacuum system with *in-situ* UV radiation

Sean R. Koebley, Ronald A. Outlaw and Randy R. Dellwo

J. Vac. Sci. Technol. A **30**, 060601 (2012); <http://dx.doi.org/10.1116/1.4754292>

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REVIEW ARTICLE

Nanoscale photon management in silicon solar cells

Sangmoo Jeong, Shuang Wang and Yi Cui

J. Vac. Sci. Technol. A **30**, 060801 (2012); <http://dx.doi.org/10.1116/1.4759260>

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PLASMA SCIENCE AND TECHNOLOGY

Frequency and electrode shape effects on etch rate uniformity in a dual-frequency capacitive reactor

Dougyong Sung, Vladimir Volynets, Wonsub Hwang, Yumi Sung, Seokhwan Lee, Myungsun Choi and Gon-Ho Kim

J. Vac. Sci. Technol. A **30**, 061301 (2012); <http://dx.doi.org/10.1116/1.4754695>

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Reaction mechanisms of oxygen plasma interaction with organosilicate low-*k* materials containing organic crosslinking groups

Mrunalkumar Chaudhari and Jincheng Du

J. Vac. Sci. Technol. A **30**, 061302 (2012); <http://dx.doi.org/10.1116/1.4755898>

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Comparison endpoint study of process plasma and secondary electron beam exciter optical emission spectroscopy

P. L. Stephan Thamban, Stuart Yun, Gabriel Padron-Wells, Jimmy W. Hosch and Matthew J. Goekner

J. Vac. Sci. Technol. A **30**, 061303 (2012); <http://dx.doi.org/10.1116/1.4756694>

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Study on breathing mode oscillation suppression of self-excited Hall thrusters

Wei Liqiu, Han Ke, Wang Chunsheng, Li Hong, Zhang ChaoHai and Yu Daren

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Study on the oxidation and reduction of tungsten surface for sub-50 nm patterning process

Jong Kyu Kim, Seok Woo Nam, Sung Il Cho, Myung S. Jhon, Kyung Suk Min, Chan Kyu

THIN FILMS

Decomposition and phase transformation in TiCrAlN thin coatings

Rikard Forsén, Mats Johansson, Magnus Odén and Naureen Ghafoor

J. Vac. Sci. Technol. A **30**, 061506 (2012); <http://dx.doi.org/10.1116/1.4757953>

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Effect of MoO₃ doping power on the electrical, optical, and structural properties of MoO₃-doped In₂O₃ anodes for organic solar cells

Yong-Hee Shin, Han-Ki Kim and Seok-In Na

J. Vac. Sci. Technol. A **30**, 061507 (2012); <http://dx.doi.org/10.1116/1.4758789>

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Transparent conductive indium zinc oxide films prepared by pulsed plasma deposition

Runlai Wan, Ming Yang, Qianfei Zhou and Qun Zhang

J. Vac. Sci. Technol. A **30**, 061508 (2012); <http://dx.doi.org/10.1116/1.4762800>

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Characterization of epitaxially grown indium islands on Si(111)

Chad Lunceford and Jeff Drucker

J. Vac. Sci. Technol. A **30**, 061509 (2012); <http://dx.doi.org/10.1116/1.4764049>

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MnP nanoclusters embedded in GaP epitaxial films grown by organometallic vapor-phase epitaxy: A reciprocal space mapping and transmission electron microscopy study

Samuel Lambert-Milot, Simon Gaudet, Christian Lacroix, David Ménard, Remo A. Masut, Christian Lavoie and Patrick Desjardins

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Apparatus for deposition of composition spread alloy films: The rotatable shadow mask

Benoit Fleutot, James B. Miller and Andrew J. Gellman

J. Vac. Sci. Technol. A **30**, 061511 (2012); <http://dx.doi.org/10.1116/1.4766194>

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Ion-induced effects on grain boundaries and a-Si:H tissue quality in microcrystalline silicon films

A. C. Bronneberg, N. Cankoy, M. C. M. van de Sanden and M. Creatore

J. Vac. Sci. Technol. A **30**, 061512 (2012); <http://dx.doi.org/10.1116/1.4766193>

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